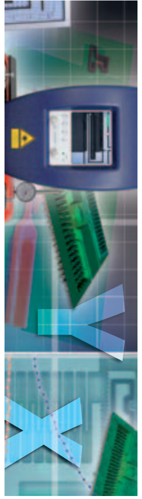

MEMUNITY-Workshop
Fraunhofer IWM Halle/Saale
March 1st 2006

Fax +49 (0)7243 604-320
Registration deadline: 22.02.06

Yes, I will attend ☐

Company
Dept.
Name
Street/No.
Zip/City
Tel. Fax
E-Mail

Participating Person(s)

☐ **No, I cannot take part, but please send me information on MEMS testing**

Affix stamp here

Polytec GmbH
Laser Measurement Systems
Polytec-Platz 1–7
76337 WALDBRONN
GERMANY

MEMUNITY
The MEMS Test Community

Program

8.30	**Coffee and Registration**
9.00	**Welcome and Introduction** Memunity – The MEMS Test Community, *Heinrich Steger, Polytec* Testing MEMS at wafer-level – general challenges, *Michael Harz, SUSS MicroTec* **Technical basics** Available wafer-level MEMS test solutions, *Frank-Michael Werner, SUSS MicroTec* **Applications** Functional and reliability testing of MEMS at IMEC: Instrumentation and methodology, *Ingrid de Wolf, IMEC* Characterisation of MEMS-Scanners by optical methods, *Steffen Kurth, Fraunhofer IZM* Non-destructive determination of membrane thicknesses by measurement of dynamic properties, *Matthias Ebert, Fraunhofer IWM*
	Lunch break
	Investigations on wafer-level Testing for Accelerometers by Harmonic Response Measurements, *Steffen Michael, Melexis* Wafer-level test of pressure sensors using Suss Pressure Probe Module (PPM), *Holger Ross, Bosch* Dynamic MEMS characterization in a production enviroment, *Jens Klattenhoff, Polytec*
14.30	**Live demonstration of manual and semiautomatic test solutions**
16.00	**Adjournment**

MEMUNITY
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Invitation

MEMUNITY-Workshop

Testing MEMS at Wafer-Level

Fraunhofer IWM Halle/Saale
March 1st 2006

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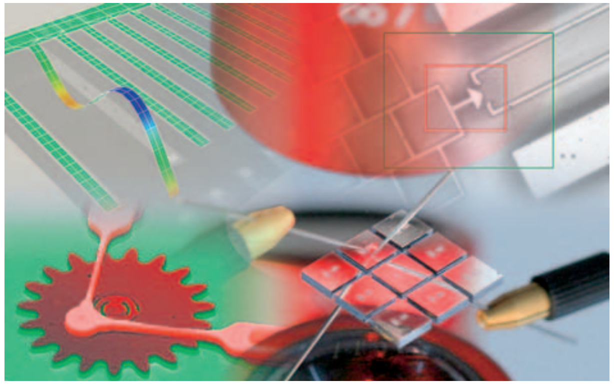
MEMUNITY-Workshop



Testing of MEMS components at different stages of fabrication and before packaging is an increasingly important challenge for achieving high yield and reliability and low production cost. Different techniques are necessary to achieve this goal. Obtain comprehensive information in this **free** workshop about solutions for testing MEMS at wafer-level. Topics are:

- **Dynamic motion analysis**
- **Reliable on-wafer test of pressure sensors**
- **Testing wafers in a vacuum**
- **Characterizing surfaces with white light interferometry**

The workshop is organized by MEMUNITY, an open community of companies and industries operating in the field of microsystems technology.
Founding organizations are:

SÜSS MicroTec

Polytec

Fraunhofer IZM
Institut Zuverlässigkeit und Mikrointegration

DELTA

Full 3-D motion analysis of MEMS with laser Doppler vibrometry and stroboscopic video microscopy plus surface topography by using white light interferometry

Testing pressure sensors directly at wafer-level

Semiautomatic and fully automated test solutions for virtually any MEMS devices

MEMUNITY-Workshop · March 1st 2006 · Halle/Saale

Polytec GmbH · Polytec Platz 1 – 7 · 76337 Waldbronn · Germany · Tel. + 49 (0) 7243 604-178/104 · LM@Polytec.de

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